

ABSTRACT

A substrate processing apparatus capable of readily addressing an increase/decrease in quantity of substrates to be processed and a change in type thereof is provided. The substrate processing apparatus includes a carrier block (B1) having first transfer means (22) for performing delivery of the substrate with respect to a substrate carrier (C) on a carrier placement portion (21), a transfer block (B2) provided adjacent to the carrier block (B1) and having second transfer means (23), a first delivery stage (24) for performing delivery of the substrate between the first transfer means (22) and the second transfer means (23), and a plurality of process blocks (B3, B4) provided to be freely attachable/detachable with respect to the transfer block (B2). Since the process blocks (B3, B4) perform a series of processing on the substrate in units of the process blocks, it is readily possible to address the considerable increase/decrease in quantity of processed substrates by attaching/detaching the process block(s), and to address the different change in type thereof by changing the process block(s).